



Atty. Dkt. No. AMAT/7034.P1/DSM/LOW K/JW

In re Application of:
Yim, et al.

Serial No.: 10/773.060

Confirmation No.: 5473

Filed: - February 4, 2004

For: Ultra Low Dielectric Materials
Based on Hybrid System of Linear
Silicon Precursor and Organic
Porogen by Plasma-Enhanced
Chemical Vapor Deposition
(PECVD)

Group Art Unit: 1762

Examiner: Marianne L. Padgett

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING
37 CFR 1.8

I hereby certify that this correspondence is being deposited on 6/9, 2005 with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

6/9/05 [Signature]
Date Signature

RESPONSE TO OFFICE ACTION DATED APRIL 14, 2005

In response to the Office Action dated April 14, 2005, having a shortened statutory period for response set to expire on July 14, 2005, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/7034.P1/KMT for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Specification are listed beginning on page 2 of this paper. **Amendments to the Claims** are reflected in the listing of claims which begins on page 4 of this paper. **Remarks** begin on page 8 of this paper.